

PATENT Docket No. 150.0056 0102

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s):	Whonchee Lee et al.)	Group Art Unit:	1765
• •		•	-	

Serial No.: 09/560,268) Examiner: Deo, Duy Vu

Confirmation No.: 2517

Filed: 26 April 2000)

Assistant Commissioner for Patents

Washington D.C. 20231

For: COMPOSITION FOR SELECTIVELY ETCHING AGAINST COBALT

SILICIDE (As Amended)

AMENDMENT AND RESPONSE

RECEIVED

MAY 1 3 2002

TC 1700

Dear Sir:

In response to the Office Action dated 4 February 2002, please amend the application as follows:

In the Claims

Please add new claims 94-96. The new claims are provided below. For convenience, all pending claims are provided in Appendix A.

508 2

94. (New) An etching composition, the composition comprising a mineral acid, a peroxide, and deionized water at a ratio in a range of about 1:1:35 (mineral acid:peroxide:deionized water) to about 1:1:5 (mineral acid:peroxide:deionized water), wherein the mineral acid is selected from the group consisting of HCl diluted to 37% by weight in deionized water, HNO₃ diluted to 70% by weight in deionized water, H₂SO₄ diluted to 96% by weight in deionized water, H₃PO₄ diluted to 85% by weight in deionized water, and HF diluted to 49% by weight in deionized water, wherein the peroxide is selected from the group consisting of hydrogen peroxide diluted to 29% by weight in deionized water, and ozone.

05/10/2002 GTEFFERA 00000138 09560268

01 FC:103 02 FC:102 54.00 OP 84.00 OP